# GROWTH KINETICS OF ANODIC ALUMINIUM OXIDE FILMS FORMED IN SULPHAMIC ACID D.KANAGARAJ, V.RAJ, M.P.RAJARAM AND G.BALASUBRAMANIAN CENTRAL ELECTROCHEMICAL RESEARCH INSTITUTE, KARAIKUDI-630006, INDIA

# INTRODUCTION

Kinetics of growth of porous anodic aluminium oxide film and their structures using Sulphuric acid, Oxalic acid, Phosphoric acid electrolytes has been studied extensively [1-5]. But kinetics of growth of oxide film on aluminium using sulphamic acid electrolyte has not yet been studied in detail. In this paper an investigation has been carried out to study the kinetics of growth of oxide film in sulphamic acid by employing the kinetic model suggested by Patermarakis etal (1) for sulphuric acid system. m=kit- $\lambda_1$ t exp ( $\lambda_2$ t) where m is the mass of oxide formed, k is the electrochemical equivalent,  $\lambda_1$  and  $\lambda_2$  are parameters depending on current density (i) and bath temperature (BT).

### **EXPERIMENT**

All 1100 aluminium alloy specimen of area 20cm² was anodized in 15% (w/v) sulphamic acid electrolyte at various current densities (1-4A/dm²) at temperatures (25°C-35°C) for various anodizing time after conventional pretreatment .The mass of the oxide film was calculated from the weight of Al before and after stripping, the thickness of oxide film was measured using dermitron thickness meter.

# RESULT AND DISCUSSION

The effect of anodizing time on mass and thickness of oxide film at various current densities and temperatures has also been studied in order to derive the various kinetic parameters such as pore volume, pore diameter, mean pore diameter, mass of dissolved oxide film, pore density, porosity, dissolution rate, true current density, activation energy to obtain information about main structural characteristics of oxide films.

It was found that true current density (i<sub>t</sub>) increases with decrease in bath temperature (BT) as indicated in column (8) of Table.1. It was also found that number of pores per unit area n as indicated in column (6) of Table.1 is not very sensitive to i variations. The parameters  $\lambda_1$  and  $\lambda_2$  as indicated in columns (3) and (4) of Table.1 are directly related to the surface area of pore base section and dissolution rate of pore wall oxide respectively. Oxide dissolution rate was found to be 0.06 to 0.13Å for oxidation temperature of 25-35°C.The mean diameter of the pore and the pore volume were calculated and are indicated in columns (10) and (11) of Table.1.It was also found that the value of  $n^{0.5}$   $k_{\rm d}$  is directly related to the current density and bath temperature as indicated in column (9) of Table.1.

It has been observed that oxide dissolution is essentially field-assisted process and thermally activated with an activation energy ( $E_a$ ) of 125.32 kJ/mol. Further results are discussed in the paper.

rable 1:Kinetic Parameters calculated for Al alloy in sulpham ic acid for various current densities at different tem peratures	10°v/m³	2.69	3.88	5.10	3.48	3.92	4.57	5.02	6.22	1.16	2.33	3.50
	D/A	272	229	203	275	249	224	212	201	294	268	242
	10°n'0.5*ka	82.	0.831	0.800	0.808	0.794	0.802	1.57	1.32	8.	1.2	1.08
	1/mA/cm <sup>2</sup>	95.4	145	179	87.7	136	178	279	365	89.01	133	176
	DDo <sup>2</sup>	0.06675	0.070788	0.071137	0.072599	0.070126	0.071536	0.068562	0.069879	0.071547	0.0718	0.072357
	10 <sup>13</sup> n/m²	9.51	1.40	1.78	8.6	1.17	48	8.	<u>\$</u>	80 80	1.06	1.31
	DovA	265	225	200	270	245	220	205	195	285	260	235
	10 <sup>3</sup> / <sub>2</sub> /min	-	20:0	9:0	9:0	9.0	9.0	1.2	-	6:0	6:0	8.0
	10³∧g/min	29.54	46,991	62,964	32.129	46.551	63.317	91.027	123.7	31,663	47,663	64,043
	I/mA /cm²	10	15	8	0	15	23	8	40	10	15	20
Table 1:Ki	BT AC	25	55	25	8	8	8	8	8	35	35	35

# References:

m

- G.Patermarakis, P.Lenas, Ch.Karavassilis and G.Papaylannis, Electrochimica Acta, 36, (1991), 709.
   G.Patermarakis and N.Papandreadis Electrochimica Acta, 38, (1993), 2351.
- 3.G.Patermarakis and D.Tzouvelekis Electrochimica Acta, 39, (1994), 2419.
- 4. G.Patermarakis and K.Moussoutzanis J.Electrochem.Soc.142, (1995), 737.
- 5. A.T.Shawaqteh and R.E.Batters J.Electrochem.Soc.145, (1998), 2699.